

U.S. Department of Commerce, Patent and Trademark Office	Serial No.: Unknown
	Filing Date: 12/21/01
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventor: Vlad J. Novotny
"Pattern-Transfer Process For Forming Micro-Electro-Mechanical Structures"	Group Art Unit: Unknown
	Examiner Name: Unknown
Express Mail Receipt No. EF055078336US	Attorney Docket No.: AO-001-1D

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
SA	AA	6,301,403 B1	10/09/01	Heanue et al.	385	18	
	AB	6,253,001 B1	06/26/01	Storrs T. Hoen	385	17	
	AC	6,028,689	02/22/00	Michalick et al.	359	224	
↓	AD	5,872,880	02/16/99	Ronald S. Maynard	385	88	
SA	AE	6,283,601 B1	09/04/01	Hagelin et al.	359	871	

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AF							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

SA	AG	"ROUTING PACKETS WITH LIGHT," Daniel J. Blumenthal. Scientific American, pages 96-99. January 2001.
	AH	"Construction and performance of a 576x576 single-stage OXC," Herzel Laor. LEOS, San Francisco, California, 3 pages. November 8, 1999.
	AI	"Application of micro- and nanotechnologies for the fabrication of optical devices," Wolfgang Ehrfeld and Hans-Dieter Bauer. SPIE Vol. 3276, page 2 and pages 4-14.
↓	AJ	"PERFORMANCE OF A 576x576 OPTICAL CROSS CONNECT," Laor, et al. NFOEC, Chicago, Illinois, pages 1-5. September 26, 1999.
SA	AK	"Control and shape design of an electrically-damped comb drive for digital switches," Yijian Chen. Proceedings of SPIE Vol. 4178, 2000. Pages 387-394.

Examiner *Shamim Ahmed*Date Considered *4/17/04*

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		Document Number	Date	Country	Class	Subclass	Yes No
	AM						
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
SA	AN	"THE RISE OF OPTICAL SWITCHING," David J. Bishop et al. Scientific American, pages 88-94. January 2001.					
	AO	"A LARGE-DEFLECTION ELECTROSTATIC ACTUATOR FOR OPTICAL SWITCHING APPLICATIONS," John D. Grade, Hal Jerman and Thomas W. Kenny. Presented at Hilton Head, 2000. 4 pages.					
	AP	"FLIP CHIP CHALLENGES," Steve Bezuk, PH.D. General Manager, Applied Technology Development and Flip Chip Kyocera America, Inc. First published in HDI Magazine, February 2000. 6 pages.					
	AQ	"MEMS Feedback Control Using Through-Wafer Optical Device Monitoring," J.M. Dawson, et al. Proceedings of SPIE Vol. 4178, 2000. Pages 221-227.					
	AR	"A FLAT HIGH-FREQUENCY SCANNING MICROMIRROR," Robert A. Conant, et al. 2000 Solid-State Sensor & Act Workshop, Hilton Head, S.C., June 4-8, 2000.					
	AS	"The Surface/Bulk Micromachining (SBM) Process: A New Method for Fabricating Released MEMS in Single Crystal Silicon," Sangwoo Lee, et al. Journal of Microelectromechanical Systems, Vol. 8, No. 4, December 1999. Pages 409-416.					
SA	AT	"MEMS actuators for silicon micro-optical elements," Norman C. Tien and Daniel T. McCormick. Proceedings of SPIE Vol. 4178, 2000. 256-267.					
Examiner		Shannon Atwood		Date Considered		11/24/04	
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Foreign Patent Documents							
							Translation
		Document Number	Date	Country	Class	Subclass	Yes No
	AV						
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
SA	AW	"Lightweight, Optically Flat Micromirrors for Fast Beam Steering," Jocelyn T. Nee, et al. Presented at IEEE/LEOS Optical MEMS 2000 Conference, August 21-4, 2000, Kauai, Hawaii, USA. 2 pages.					
SA	AX	"Optical MEMS for Optical Communications - Trends and Developments," Veljko Milanovic. Adriatic Research Institute. Pages 2-6. Downloaded December 20, 2001.					
	AY						
	AZ						
	BA						
	BB						
Examiner		Shamim Ahmed		Date Considered		11/24/04	
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SA	BC	6,252,466 B1	06/26/01	J. Patrick Kawamura	331	25	
SA		6,097,859	08/01/00	Solgaard et al.	385	17	
Foreign Patent Documents							
							Translation
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	BD						
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SA	BE	Topical Review "The future of MEMS in telecommunications networks," James A. Walker. J. Micromech, Microeng.10(2000)R1-R7. Printed in the UK.					
	BF	D.J. Bishop Presentation, "Silicon Micromachines for Lightwave Networks: Can Little Machines Make it Big?" Lucent Technologies, Bell Labs Innovations. 83 pages. Date unknown.					
	BG						
	BH						
	BI						
	BJ						
Examiner		Shamin Arif		Date Considered		11/24/04	
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